**Emission monitors flow**

**Flowsic 100 stack flow monitors**

***Description:***

The product family FLOWSIC100 was designed for emission monitoring tasks. The "H" versions are suitable for stacks with large diameters and applications with high dust content. The "M" versions are especially suited for stacks with medium diameter. The ultrasonic transducers of the "PR" probe type are mounted with fixed path length on one sender/receiver unit (measuring probe). The "AC" versions have an innovative internal cooling and are suitable for gas temperatures up to 450 °C. The purged "Px" versions are used for gases with high concentrations of sticky or wet dust.
Rugged titanium transducers are standard and suitable under difficult conditions. The measuring system consists of 2 sender/receiver units or a measuring probe and a MCU control unit. The MCU is used for input and output of signals, for calculation of volume flow to reference conditions (standardization) as well as user-friendly LCD interface.

**Specification:**

Measured values: Volumetric flow, a. c., volumetric flow s. c., gas velocity, sound velocity, gas temperature

Gas temperature: –40 °C ... +450 °C

Operating pressure: –100 hPa ... 100 hPa

Nominal pipe size: 0.15 m ... 13 m

Depending on device version

Conformities:
2001/80/EC (13. BImSchV)
2000/76/EC (17. BImSchV)
27.BImSchV
30. BImSchV
TA-Luft (Prevention of Air Pollution)
EN 15267
EN 14181
EN 16911-2
MCERTS
GOST

Enclosure rating: IP65